

***Amendments to the Claims***

The listing of claims will replace all prior versions, and listings, of claims in the application.

1. *(Canceled)*
2. *(Currently Amended)* The method of claim [[1]] 20, wherein the machine part is transported from the environment through [[via]] the load lock into the interior space after cleaning the machine part ~~outside the interior space~~ and the machine part is transported after being maintained from the environment through [[via]] the load lock into the interior space.
3. *(Currently Amended)* The method of claim [[1]] 20, wherein the separate replacement machine part is transported from the environment through [[via]] the load lock into the interior space and the separate replacement machine part is a clean version of the machine part and the separate replacement machine part is transported from the environment through [[via]] the load lock into the interior space as a clean version of the machine part.
4. *(Currently Amended)* The method of claim [[1]] 20, where the machine part is connected to and disconnected from the machine via a connection system.
5. *(Previously Presented)* The method of claim 4, wherein the connection system self-aligns during connecting and disconnecting.

6. *(Currently Amended)* The method of claim [[1]] 20, wherein the machine part is the substrate table and further comprising:  
displacing the substrate table with respect to a chuck by a displacement mechanism.
7. *(Previously Presented)* The method of claim 6, wherein displacing the substrate table with respect to the chuck comprises:  
moving at least one of a pin, that in a first position extends in a first direction through the substrate table, and the substrate table in a second direction, which is substantially perpendicular to the first direction, when the pin is at a second position that does not extend through the substrate table; and  
displacing the substrate table with respect to the chuck by moving the pin in the first direction.
8. *(Previously Presented)* The method of claim 7, wherein the movement of the at least one of the pin and the substrate table in the second direction is a rotation.
9. *(Currently Amended)* The method of claim [[1]] 20, where the machine is a lithographic projection apparatus configured to project a beam of radiation on the substrate.

10. (*Previously Presented*) The method of claim 9, wherein the transporting the machine part includes grasping the gripper arranged to grip and release the substrate and/or the substrate table.

11. (*Canceled*)

12. (*Currently Amended*) The assembly of claim [[11]] 21, wherein said apparatus assembly is a lithographic projection apparatus comprising:

a radiation system ~~constructed and arranged~~ configured to provide a beam of radiation;

a support structure to support a patterning device, said patterning device serving to pattern said beam according to a desired pattern; and

a projection system ~~constructed and arranged~~ configured to project said patterned beam onto a target portion of said substrate.

13. (*Currently Amended*) The assembly of claim [[11]] 21, further comprising:

a cleaning apparatus ~~constructed and arranged~~ configured to clean said machine part outside said interior space to render it as said machine part after maintenance that can be transported ~~via said load lock~~ from said environment into said interior space through said load lock.

14. (*Currently Amended*) The assembly of claim [[11]] 21, wherein said separate replacement part is a clean version of said machine part that can be transported ~~via said load lock~~ from said environment into said interior space through said load lock.

15. *(Currently Amended)* The assembly of claim [[11]] 21, further comprising:  
a connection system ~~constructed and arranged~~ configured to connect and disconnect said machine part from said apparatus assembly.
16. *(Currently Amended)* The assembly of claim 15, wherein said connection system is ~~constructed and arranged~~ configured to be self-aligning during connecting and disconnecting.
17. *(Currently Amended)* The assembly of claim [[11]] 21, wherein said machine part is the substrate table and further ~~comprising~~ comprising:  
a displacement mechanism to displace the substrate table with respect to a chuck.
18. *(Currently Amended)* The method of claim 6, wherein displacing the substrate table by the displacement mechanism ~~includes~~ includes:  
providing the displacement mechanism having a pin, which in a first position can extend in a first direction through the substrate table, and that displaces the substrate table with respect to the chuck through movement of the pin in the first direction; and  
a shifting mechanism moving at least one of the pin and the substrate table in a second direction, which is substantially perpendicular to the first direction, when the pin is at a second position that does not extend through the substrate table.

19. *(Previously Presented)* The method of claim 18, where said movement of said at least one of the pin and said substrate table in said second direction is a rotation.
20. *(New)* A method of maintaining a machine part arranged in an interior space of a machine, where the interior space is kept at a first pressure and is separated from an environment having a second pressure by a load lock, the method comprising:
  - engaging the machine part with a first handler, wherein the first handler has either a plurality of tapered protrusions or a plurality of tapered grooves that substantially correspond to, respectively, a plurality of tapered grooves or a plurality of tapered protrusions located on the machine part;
  - transporting the machine part from the interior space to the load lock using the first handler;
  - disengaging the machine part from the first handler;
  - engaging the machine part with a second handler, wherein the second handler has either a plurality of tapered protrusions or a plurality of tapered grooves that substantially correspond to, respectively, a plurality of tapered grooves or a plurality of tapered protrusions located on the machine part;
  - transporting the machine part from the load lock to the environment using the second handler;
  - disengaging the machine part from the second handler;
  - performing maintenance on or replacement of the machine part;
  - engaging the machine part with the second handler;

transporting the maintained or replaced machine part from the environment to the load lock;  
disengaging the machine part from the second handler;  
engaging the machine part with the first handler; and  
transporting the maintained or replaced machine part from the load lock to the interior space;  
wherein the machine part is a substrate table configured to support a substrate or a gripper configured to grip and release the substrate and/or the substrate table.

21. (New) An assembly having an interior space maintained at a first pressure and an environment having a second pressure, comprising:

a load lock separating the interior space from the environment;  
a first handler, located at a first side of said load lock, having a first plurality of tapered protrusions or tapered grooves that substantially correspond to and engage a second plurality of tapered grooves or tapered protrusions located on a machine part;  
a second handler, located at a second side of said load lock, having a third plurality of tapered protrusions or tapered grooves that substantially correspond to and engage the second plurality of tapered grooves or tapered protrusions of the machine part; and  
means for maintaining the first pressure when said load lock is open to the interior space,

wherein said first handler is configured to transfer the machine part between the interior space to the load lock, and said second handler is configured to transfer the machine part between the load lock to the environment, and wherein the machine part comprises one of a substrate table configured to support a substrate and a gripper configured to manipulate at least one of the substrate and the substrate table.